

ABSTRACT OF THE DISCLOSURE

A substrate transfer apparatus, for removing a substrate from a substrate accommodating tray accommodating the substrate in a horizontal state, includes a plurality of support pins for raising the substrate accommodated in the substrate accommodating tray above the substrate accommodating tray. The substrate accommodating tray includes a plurality of openings through which the plurality of support pins are to be inserted. The plurality of support pins are moved up relative to the substrate accommodating tray and are inserted through the plurality of openings of the substrate accommodating tray, so as to raise the substrate. The plurality of support pins each have a length sufficient to be vertically inserted through a plurality of substrate accommodating trays stacked vertically.